


FIG.1A

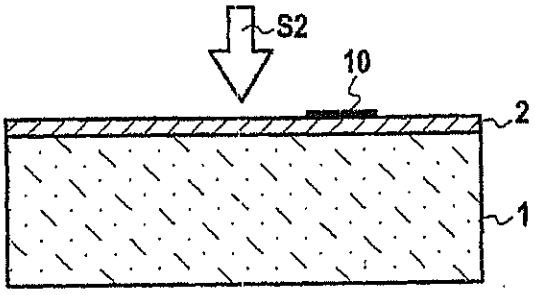



FIG.1B

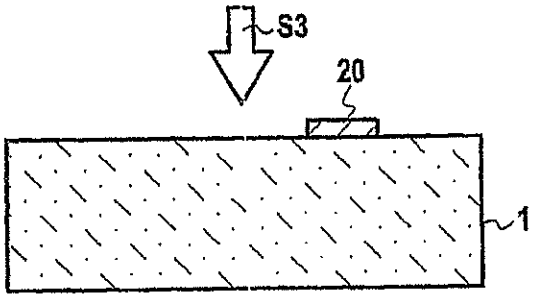



FIG.1C

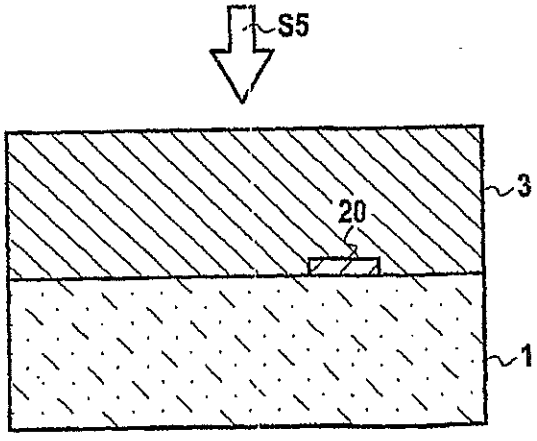



FIG.1D

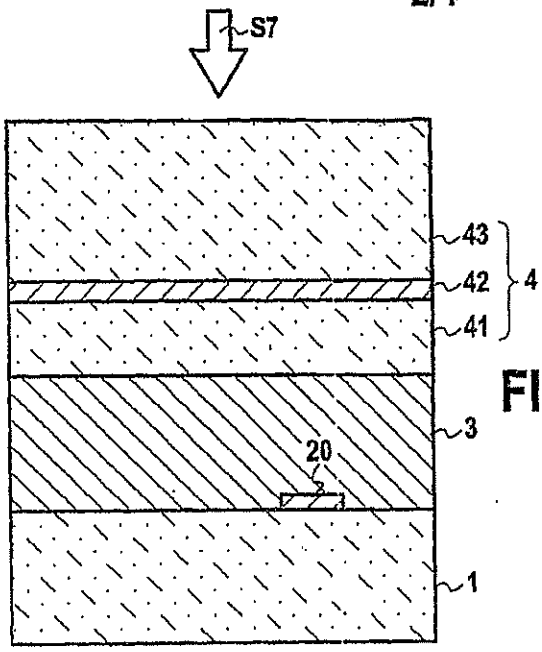



FIG.1E

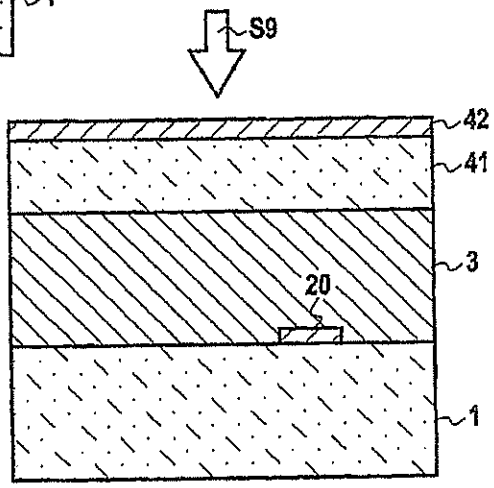



FIG.1F

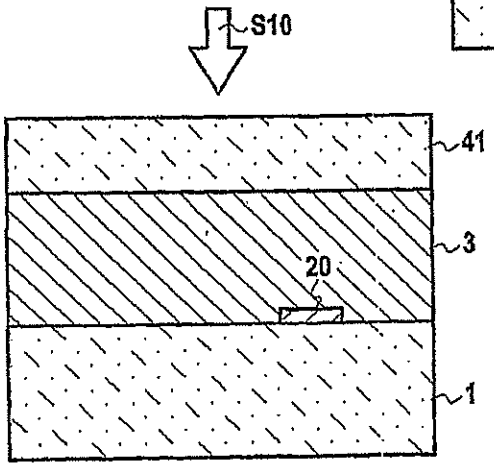



FIG.1G

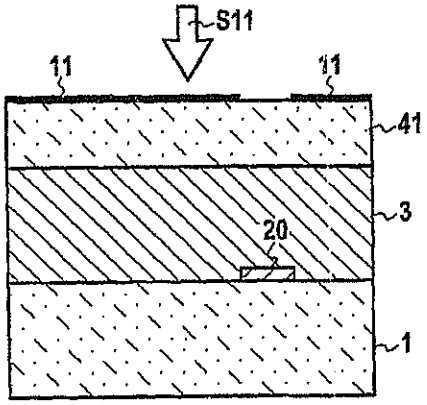



FIG.1H

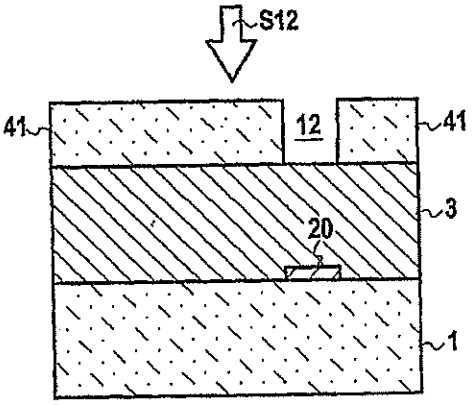



FIG.1I

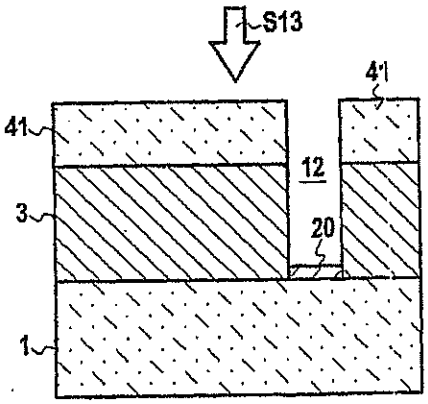



FIG.1J

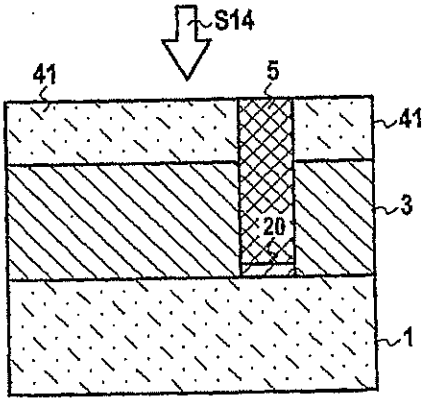



FIG.1K

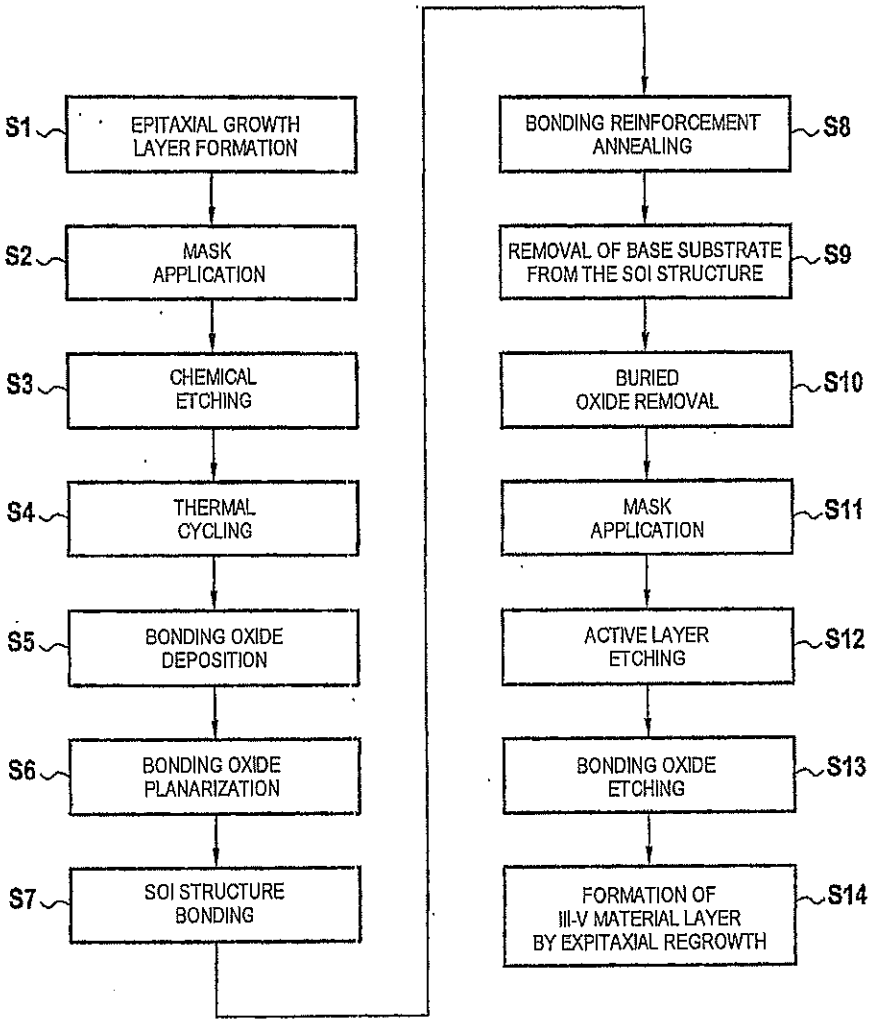

S1
EPITAXIAL GROWTH LAYER FORMATION
S2
MASK APPLICATION
S3
CHEMICAL ETCHING
S4
THERMAL CYCLING
S5
BONDING OXIDE DEPOSITION
S6
BONDING OXIDE PLANARIZATION
S7
SOI STRUCTURE BONDING
S8
BONDING REINFORCEMENT ANNEALING
S9
REMOVAL OF BASE SUBSTRATE FROM THE SOI STRUCTURE
S10
BURIED OXIDE REMOVAL
S11
MASK APPLICATION
S12
ACTIVE LAYER ETCHING
S13
BONDING OXIDE ETCHING
S14
FORMATION OF III-V MATERIAL LAYER BY EXPITAXIAL REGROWTH

FIG.2